



AF/ISW

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Hou, Chien-Chou; et al.)	Examiner:	Deo, Duy Vu Nguyen
Serial No.:	10/600,377)	Art Unit:	1765
Filed:	June 20, 2003)	Our Ref:	B-5130 621033-6
For:	"METHOD OF ETCHING UNIFORM SILICON LAYER")	Date:	August 23, 2006
)	Re:	<i>Response to Final</i>

RESPONSE TO FINAL

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in reply to the final Office Action mailed on June 23, 2006, a response to which is due no later than

September 23, 2006.

Please consider the following remarks. **All remarks herein are made without prejudice**

Remarks/Arguments begin on Page 2 of this Response.